



US009327457B2

(12) **United States Patent**
Uchida et al.

(10) **Patent No.:** **US 9,327,457 B2**
(45) **Date of Patent:** ***May 3, 2016**

(54) **ELECTRONIC DEVICE AND METHOD FOR
MANUFACTURING ELECTRONIC DEVICE**

(2013.01); *H01L 2224/97* (2013.01); *H01L*
2924/1461 (2013.01); *H01L 2924/15788*
(2013.01); *H01L 2924/1815* (2013.01)

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(58) **Field of Classification Search**

USPC 264/160, 272.11, 272.14; 438/126, 127;
257/E21.599

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See application file for complete search history.

(*) Notice: Subject to any disclaimer, the term of this
patent is extended or adjusted under 35
U.S.C. 154(b) by 640 days.

This patent is subject to a terminal dis-
claimer.

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(21) Appl. No.: **13/591,600**

(22) Filed: **Aug. 22, 2012**

(65) **Prior Publication Data**

US 2012/0322208 A1 Dec. 20, 2012

Related U.S. Application Data

(62) Division of application No. 12/213,967, filed on Jun.
26, 2008, now Pat. No. 8,270,177.

(30) **Foreign Application Priority Data**

Jul. 27, 2007 (JP) 2007-195683
Dec. 13, 2007 (JP) 2007-321587

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(51) **Int. Cl.**

H01L 21/56 (2006.01)
B29C 70/72 (2006.01)

(Continued)

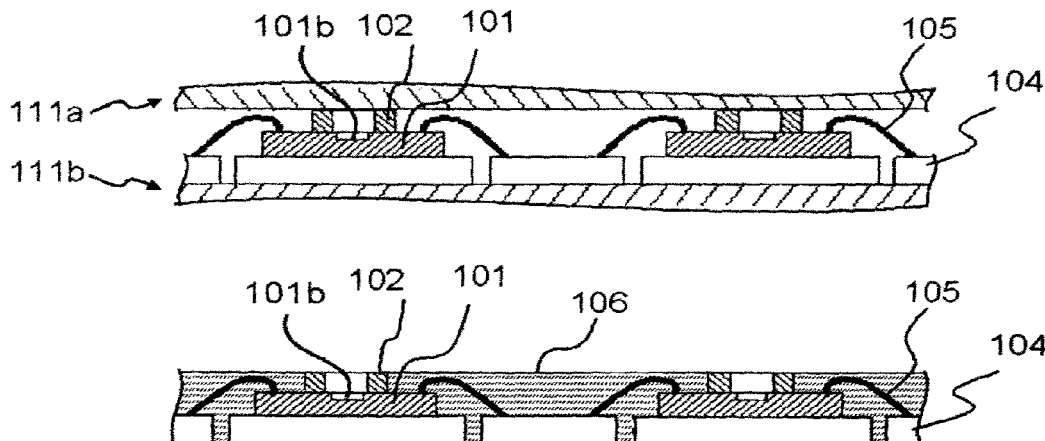
(57) **ABSTRACT**

A method for manufacturing an electronic device includes
forming a resin film over a wafer, the wafer including a
plurality of elements formed therein, each of the elements
including a functional unit, patterning the resin film to form a
plurality of frame members, each of the frame members being
provided on each of the elements and surrounding the func-
tional unit, dividing the wafer into the elements, and provid-
ing an encapsulation.

(52) **U.S. Cl.**

CPC **B29C 70/72** (2013.01); **B29C 45/14**
(2013.01); **B29C 45/14639** (2013.01); **H01L**
21/56 (2013.01); **H01L 24/97** (2013.01); **H01L**
31/0203 (2013.01); **H01L 31/18** (2013.01);
H01L 2224/48091 (2013.01); **H01L 2224/48247**

20 Claims, 14 Drawing Sheets



- (51) **Int. Cl.**
B29C 45/14 (2006.01)
H01L 31/0203 (2014.01)
H01L 31/18 (2006.01)
H01L 23/00 (2006.01)
H01L 23/28 (2006.01)
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FIG. 1A

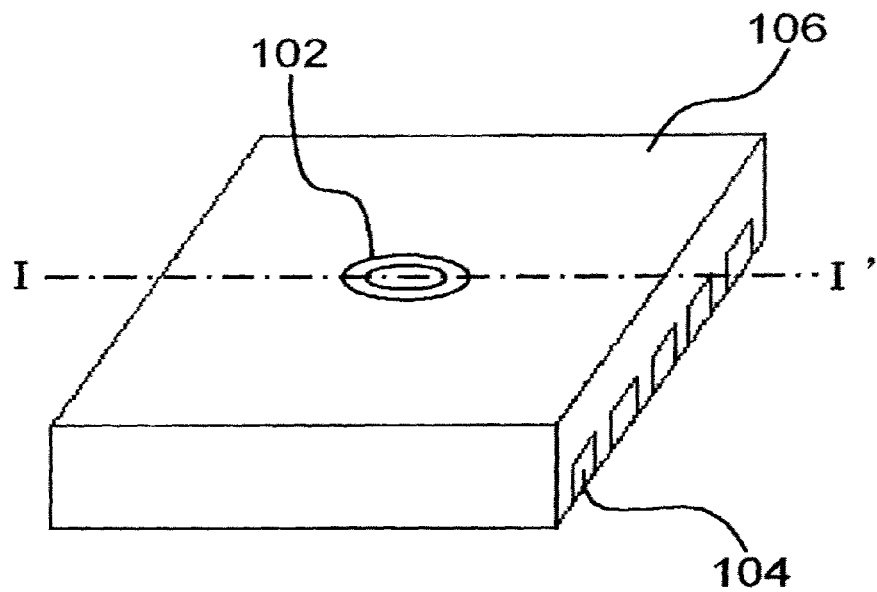


FIG. 1B

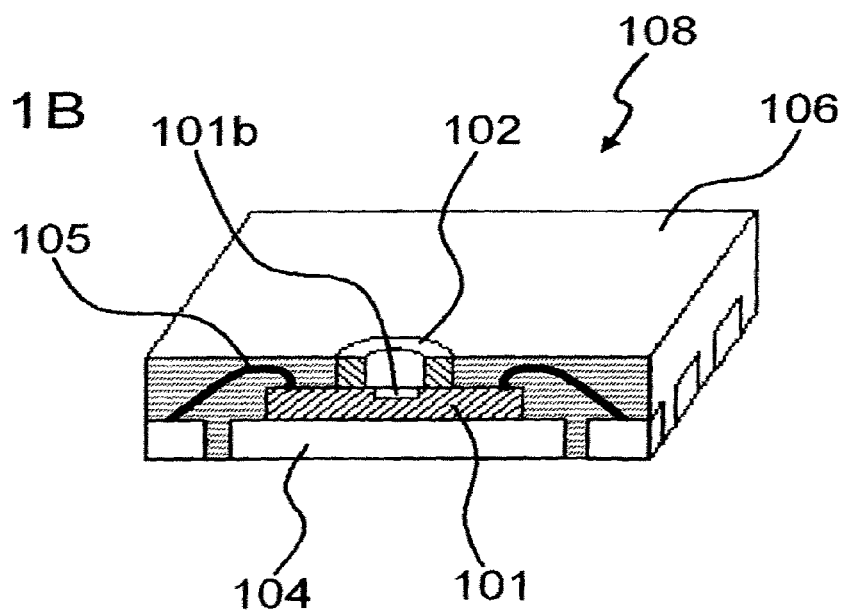


FIG. 2A

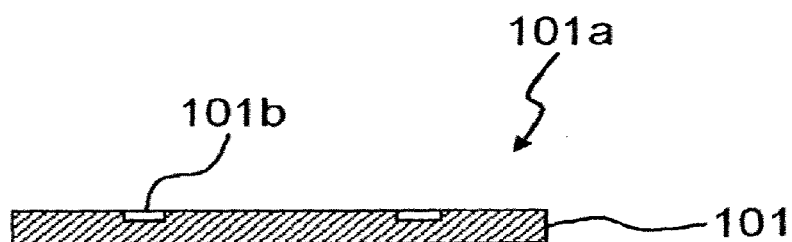


FIG. 2B

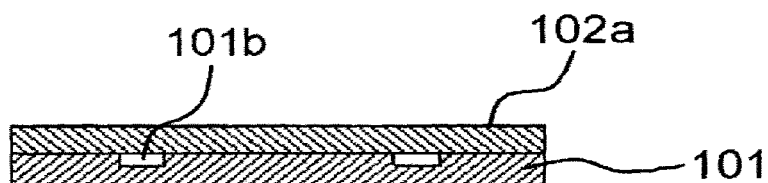


FIG. 2C

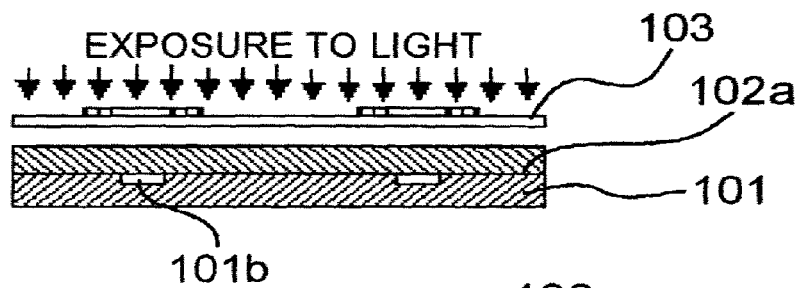
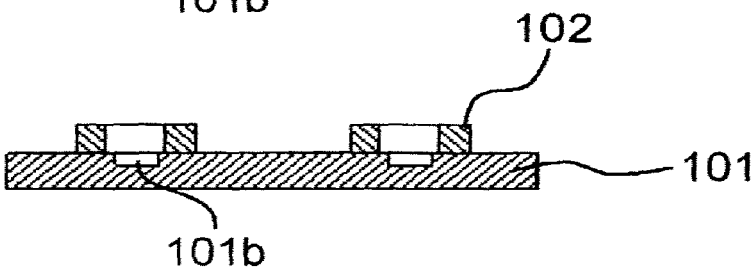


FIG. 2D



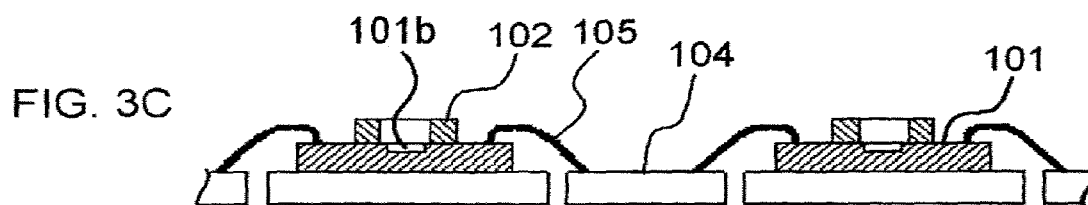
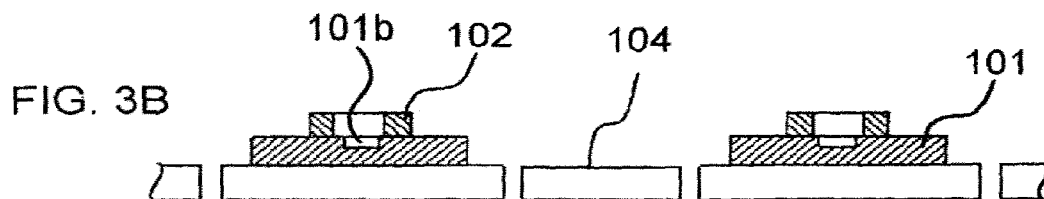
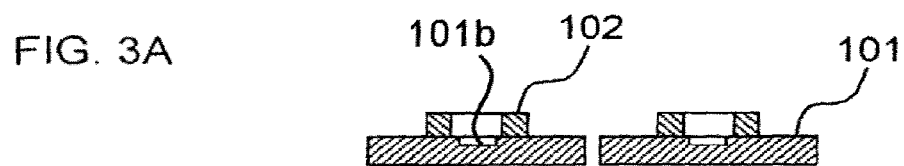


FIG. 4A

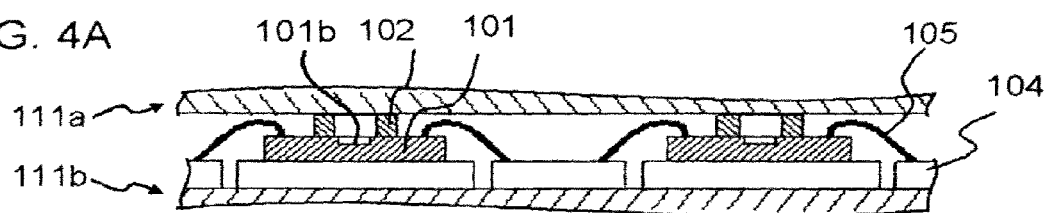


FIG. 4B

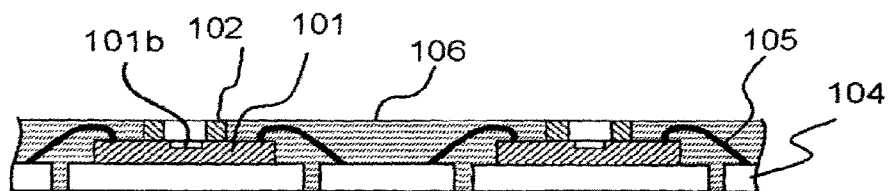


FIG. 5A

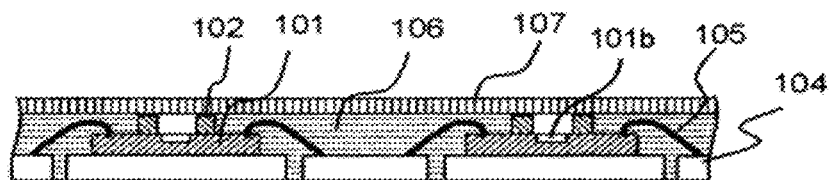


FIG. 5B

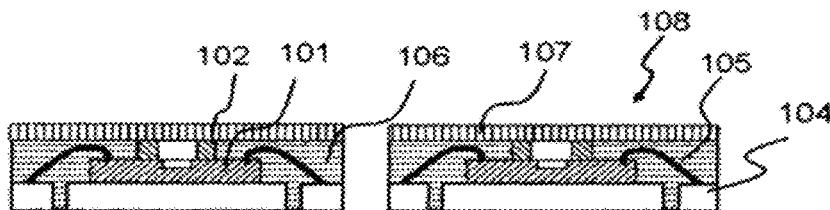


FIG. 5C

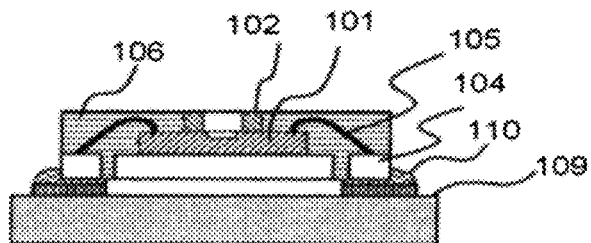


FIG. 6A

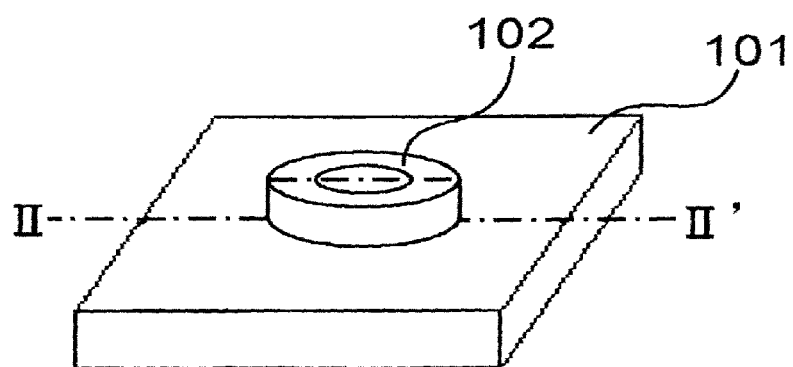


FIG. 6B

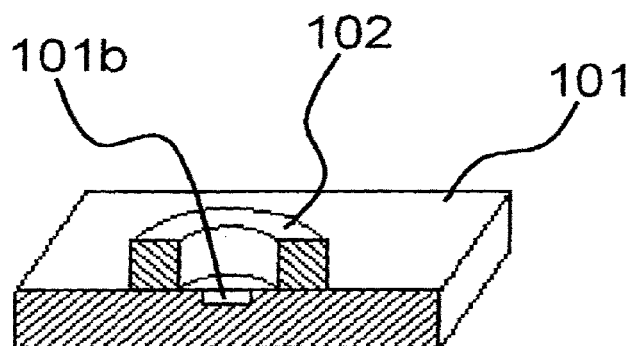


FIG. 7A

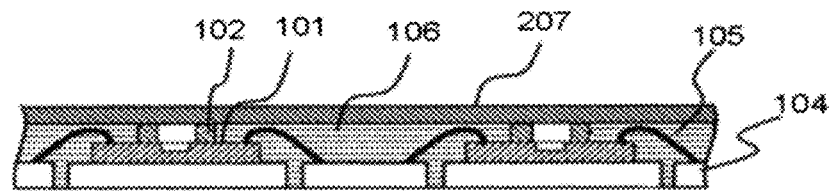


FIG. 7B

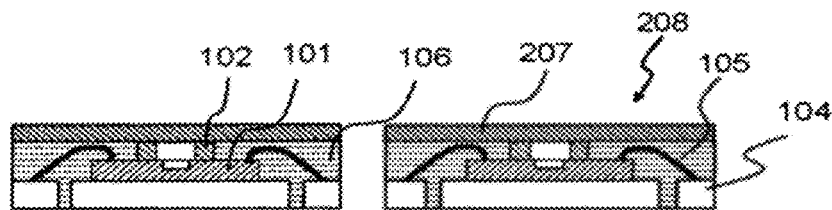


FIG. 7C

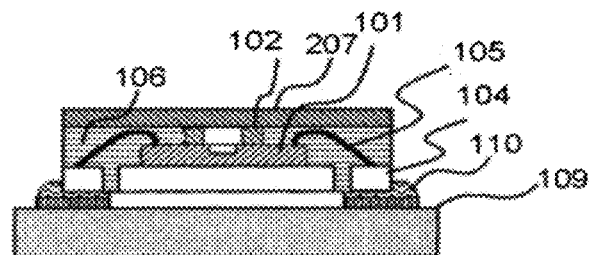


FIG. 8A

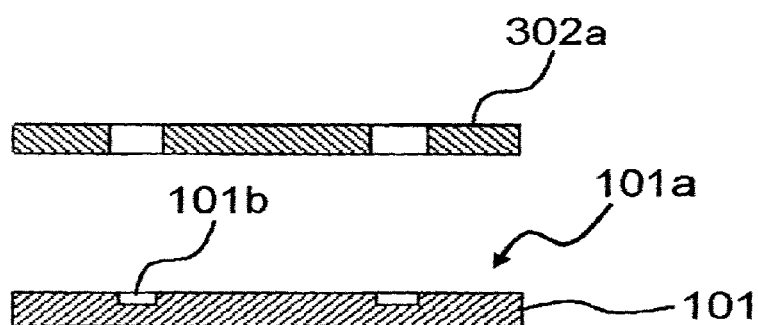


FIG. 8B

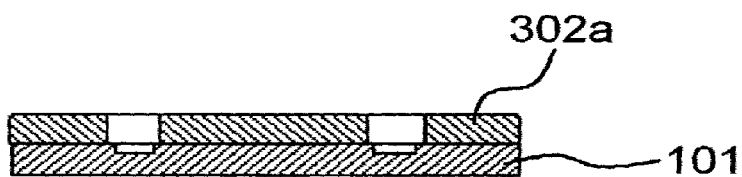


FIG. 8C

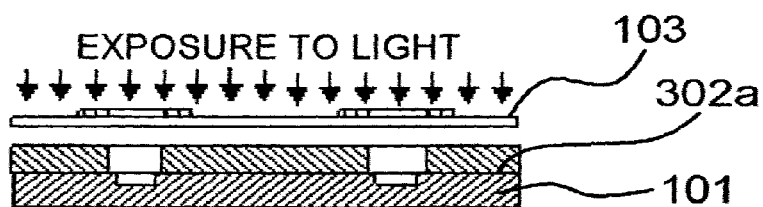


FIG. 8D

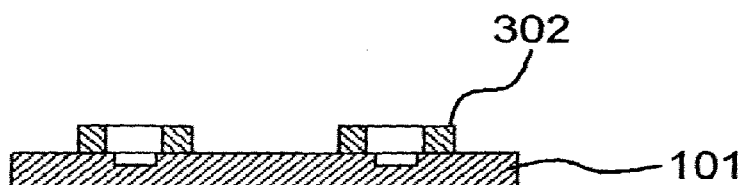


FIG. 9A

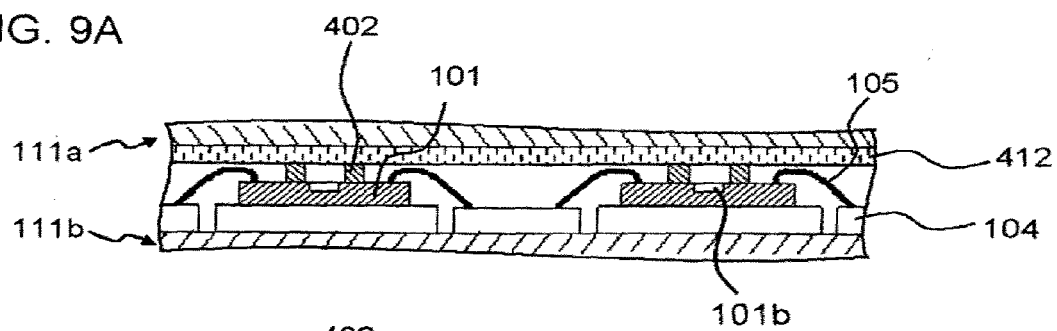


FIG. 9B

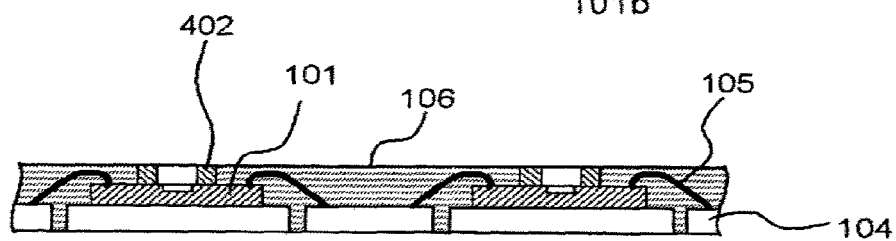


FIG. 10A

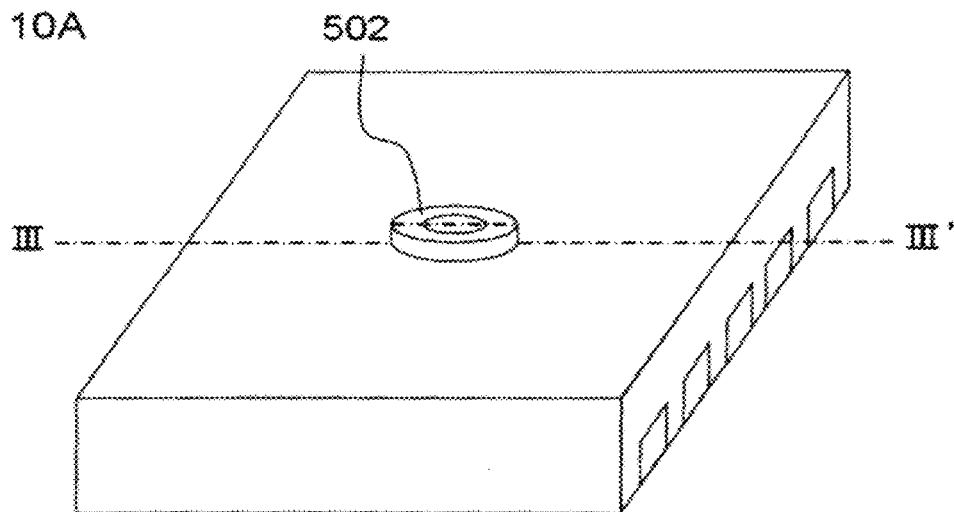


FIG. 10B

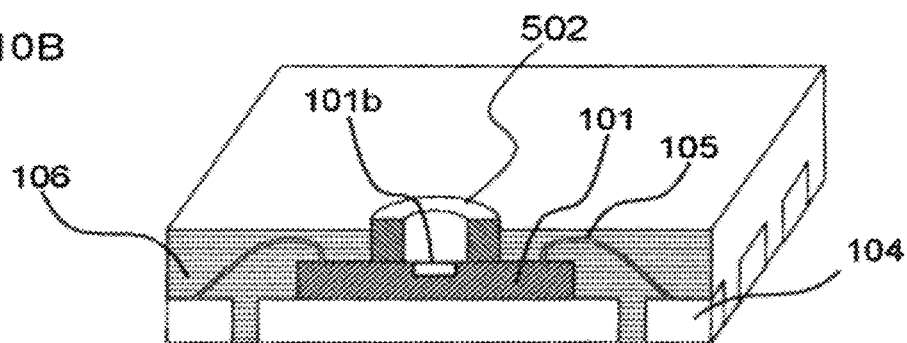


FIG. 11A



FIG. 11B

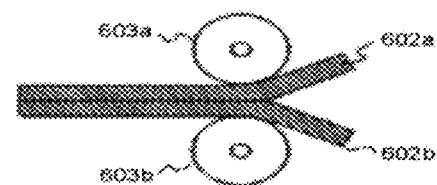


FIG. 11C



FIG. 11D



FIG. 11E



FIG. 11F

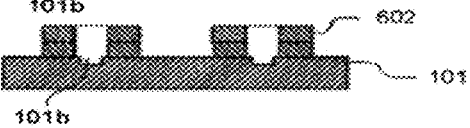


FIG. 11G

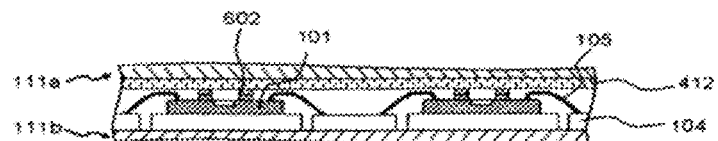
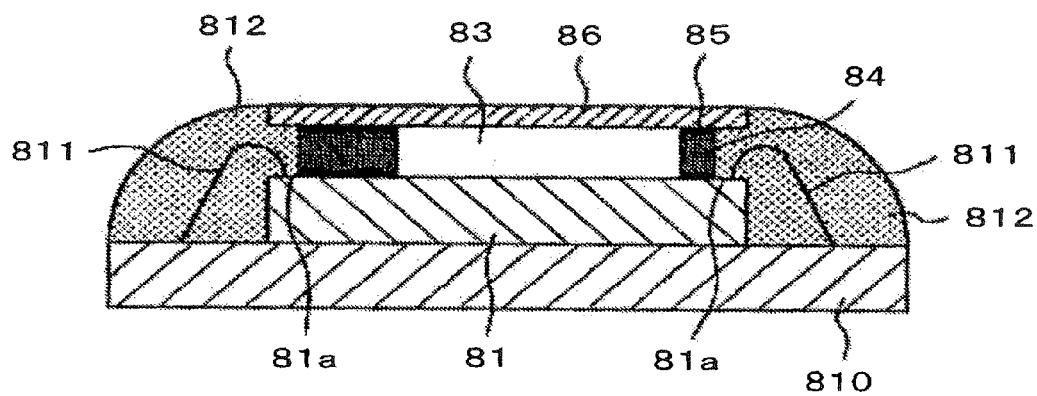
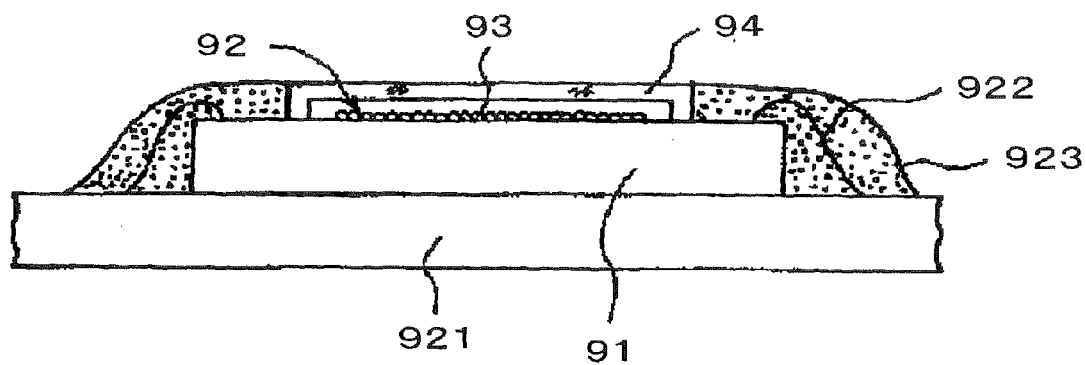


FIG. 12



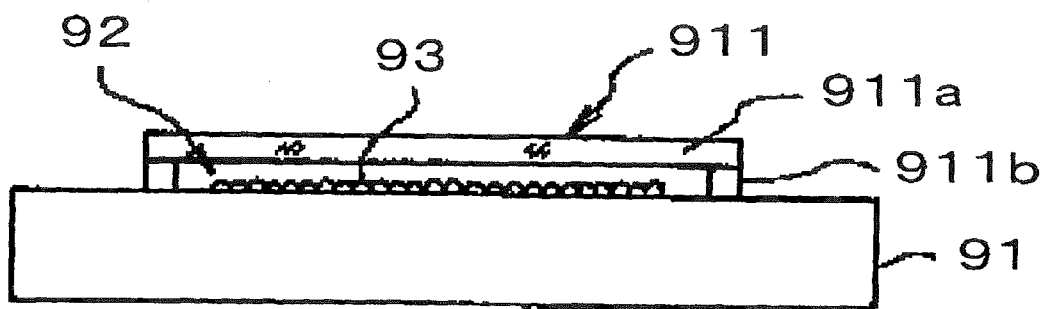
"Related Art"

FIG. 13



"Related Art"

FIG. 14



"Related Art"

ELECTRONIC DEVICE AND METHOD FOR MANUFACTURING ELECTRONIC DEVICE

The present application is a Divisional Application of U.S. patent application Ser. No. 12/213,967, filed on Jun. 26, 2008, now U.S. Pat. No. 8,270,177 which is based on and claims priority from Japanese patent applications No. 2007-195683 and No. 2007-321587, the contents of which are incorporated hereinto by reference.

BACKGROUND

1. Technical Field

The present invention relates to an electronic device and a method for manufacturing an electronic device.

2. Related Art

Electronic devices having exposed portions in functional elements are being developed for practical uses to meet the needs in recent technological advances. The developments of such type of devices are based on requirements for reducing an attenuation of an optical signal and an improved moisture resistance of electronic devices for meeting with a reflow condition in mounting a lead free by employing a black resin in an electronic device that converts an optical signal into an electrical signal and directly introduces an optical signal entered from an outside of the electronic device into a photo acceptance of the optical device. In particular, in optical recording technologies utilizing blue light as an optical signal, epoxy resins employed in light-receiving devices for transforming the optical signals into electrical signals are deteriorated by the blue light to be in failure condition, and therefore, the above-mentioned electronic devices having exposed portions in functional elements, in which epoxy resin is eliminated from the optical path, are required. In addition, the electronic devices having such structure include movable elements in functional elements such as micro electro-mechanical systems (MEMS), electric acoustic filters and the like, and the above-described types of electronic devices are expected to be adopted for devices having movable elements that cannot be encapsulated with a resin or for solid-state image sensing elements for cameras.

FIG. 12 is a cross-sectional view, illustrating a solid-state imaging device described in Japanese Patent Laid-Open No. 2001-257,334. As shown in FIG. 12, a solid-state imaging device includes a solid-state image sensing element chip 81, an epoxy resin sheet 84 having an opening portion 83 formed only in a photo acceptance unit (not shown) adhered on the solid-state image sensing element chip 81 with an adhesive agent 85, and a transparent member 86 adhered on the epoxy resin sheet 84 with the adhesive agent 85 and serving as a flat plate portion. The solid-state image sensing element chip 81 is die-bonded to a package or substrate 810, and certain couplings between a pad portion 81a of the solid-state image sensing element chip 81 and the package or substrate 810 are made by bonding wires 811 to achieve a practical use thereof, and then peripheral portions thereof including bonding wire-coupling portions except hermetic seals are packaged with an encapsulating resin 812. A transparent member 86 functions as a protective film for a photo acceptor.

FIG. 13, 14 are cross-sectional views, illustrating a solid-state imaging device described in Japanese Patent Laid-Open No. H07-202,152 (1995). As shown in FIG. 13, a solid-state imaging device includes a solid-state image sensing element chip 91, in which only a photo acceptance area 92 provided with a micro lens 93 is hermetically sealed with a transparent encapsulating member 94. The solid-state image sensing element chip 91 is directly adhered onto a substrate 921 by a

die-bonding, and after the electrodes of the solid-state image sensing element chip 91 is connected to the electrodes of the substrate 921 by the bonding wires 922, the chip surfaces except the transparent encapsulating member 94 provided only in the photo acceptance area 92 of the solid-state image sensing element chip 91 and the coupling portions with the bonding wires 922 are encapsulated with the encapsulating resin 923. As shown in FIG. 14, the transparent encapsulating member 911 includes a flat plate portion 911a and a frame 911b and is configured to form the flat plate portion 911a on the upper surface of the frame 911b. The transparent encapsulating member 911 provides a protection of the photo acceptance area 92, and the flat plate portion 911a functions as a protective film. A transparent encapsulating member 911 shown in FIG. 14 corresponds to the transparent encapsulating member 94 shown in FIG. 13.

Besides, the upper surface of the encapsulating resin 812 is located to be higher than the upper surface of the epoxy resin sheet 84 in the solid-state imaging device described in reference to FIG. 12. Therefore, the side surfaces of the transparent member 86 formed on the epoxy resin sheet 84 are covered with the encapsulating resin 812. This provides an adhesion of the side surface of the transparent member 86 with the encapsulating resin 812, and thus stripping of the transparent member 86 is difficult.

In the solid-state imaging device described in reference to FIGS. 13 and 14, the upper surface of the encapsulating resin 923 is located to be higher than the upper surface of the frame 911b. Since the side surface of the transparent encapsulating member 94 is covered with the encapsulating resin 923 as shown in FIG. 13, the side surface of the flat plate portion 911a shown in FIG. 14 is covered with the encapsulating resin 923 (not shown). This causes an adhesion of the side surface of the flat plate portion 911a with the encapsulating resin 923, causing a difficulty in stripping the flat plate portion 911a. In addition, since the dimensional area of a surface for adhesion of the flat plate portion 911a is limited by the dimensional area of the upper surface of the frame 911b, it is difficult to provide an increased dimensional area for adhesion to achieve higher adhesive force.

SUMMARY

According to one aspect of the present invention, there is provided an electronic device, comprising: an element; a frame member composed of a first resin provided so as to surround a functional unit of the element; and a resin layer composed of a second resin and filling a periphery of the frame member, wherein the functional unit of the element is exposed in a space surrounded by the frame member, and wherein an upper surface of the frame member and an upper surface of the resin layer form a common plane, or the upper surface of the frame member is located to be higher than the upper surface of the resin layer.

In such electronic device, the upper surface of the frame member and the upper surface of the resin layer are coplanar, or the upper surface of the frame member is located to be higher than the upper surface of the resin layer. More specifically, attaching and removing of the protective film that covers the upper surface of frame member and the upper surface of the resin layer can be facilitated, so that a reduced contamination in the functional unit can be achieved, providing an electronic device with an improved reliability.

According to another aspect of the present invention, there is provided an electronic device, comprising: an element; a frame member composed of a first resin provided so as to surround a functional unit of the element; and a resin layer

composed of a second resin and filling a periphery of the frame member, wherein the functional unit of the element is exposed in a space surrounded by the frame member, and wherein an upper surface of the frame member is located to be higher than an upper surface of the resin layer.

In such electronic device, the upper surface of the frame member is located to be higher than the upper surface of the resin layer. More specifically, attaching and removing of the protective film that covers the upper surface of frame member and the upper surface of the resin layer can be facilitated, so that a reduced contamination in the functional unit can be achieved, providing an electronic device with an improved reliability.

According to further aspect of the present invention, there is provided a method for manufacturing an electronic device, including: (a) forming a resin film over a wafer, the wafer including a plurality of elements formed therein, each of the elements including a functional unit;

(b) patterning the resin film to form a plurality of frame members, the each of the frame members being provided on each of the elements and surrounding the functional unit;

(c) dividing the wafer into the elements; and

(d) providing an encapsulation, including:

(i) installing at least one of the elements over a base member;

(ii) pressing a molding surface of a first encapsulating metal mold and a molding surface of a second encapsulating metal mold against an upper surface of a frame member of the frame members and a lower surface of the base member, respectively;

(iii) injecting an encapsulating resin into a space surrounded by the molding surfaces of the first and second encapsulating metal molds but other than into a space surrounded by the frame member, thereby forming an encapsulating resin layer in a periphery of the frame member; and

(iv) removing the first and second encapsulating metal molds, wherein the upper surface of the frame member is located higher than an upper surface of the encapsulating resin layer after (iv).

Since the molding surface of the encapsulating metal mold is pressed against the upper surface of the frame member and the lower surface of the base member, and the second resin is injected into portions of spaces surrounded by the molding surface of the encapsulating metal mold except the portion surrounded by the frame member to fill a periphery of the frame member in such method for manufacturing the electronic device, the upper surface of the frame member and the upper surface of the resin layer are formed to be coplanar. This allows easy attaching and removing of the protective film that covers the plane formed of the upper surface of frame member and the upper surface of the resin layer can be facilitated, so that a reduced contamination in the functional unit can be achieved, providing an electronic device with an improved reliability. This provides the electronic device with an improved reliability by a simple process.

According to the present invention, an electronic device can be provided with an improved reliability and a reduced contamination in a functional unit of an exposed element, and a method for manufacturing thereof is also provided.

BRIEF DESCRIPTION OF THE DRAWINGS

The above and other objects, advantages and features of the present invention will be more apparent from the following description of certain preferred embodiments taken in conjunction with the accompanying drawings, in which:

FIG. 1A is a perspective view, illustrating an electronic device in first embodiment, and FIG. 1B is a cross-sectional view of the electronic device shown in FIG. 1A along line I-I'.

FIGS. 2A to 2D are cross-sectional views, illustrating a process for manufacturing the electronic device in first embodiment;

FIGS. 3A to 3C are cross-sectional views, illustrating the process for manufacturing the electronic device in first embodiment;

FIGS. 4A and 4B are cross-sectional views, illustrating the process for manufacturing the electronic device in first embodiment;

FIGS. 5A to 5C are cross-sectional views, illustrating the process for manufacturing the electronic device in first embodiment;

FIG. 6A is a perspective view, illustrating another electronic device in first embodiment, and FIG. 6B is a cross-sectional view of the electronic device shown in FIG. 6A along line II-II'.

FIGS. 7A to 7C are cross-sectional views, illustrating a process for manufacturing the electronic device in second embodiment;

FIGS. 8A to 8D are cross-sectional views, illustrating a process for manufacturing the electronic device in third embodiment;

FIG. 9A and FIG. 9B are cross-sectional views, illustrating a process for manufacturing the electronic device in fourth embodiment;

FIG. 10A is a perspective view, illustrating an electronic device in fifth embodiment, and FIG. 10B is a cross-sectional view of the electronic device shown in FIG. 10A along line III-III'.

FIGS. 11A to 11G are cross-sectional views, illustrating a process for manufacturing the electronic device in sixth embodiment;

FIG. 12 is a cross-sectional view, illustrating a conventional electronic device;

FIG. 13 is a cross-sectional view, illustrating a conventional electronic device; and

FIG. 14 is a cross-sectional view, illustrating a conventional electronic device.

DETAILED DESCRIPTION

The invention will be now described herein with reference to illustrative embodiments. Those skilled in the art will recognize that many alternative embodiments can be accomplished using the teachings of the present invention and that the invention is not limited to the embodiments illustrated for explanatory purposed.

Exemplary implementations for electronic devices and methods for manufacturing thereof according to the present invention will be described in detail as follows in reference to the annexed figures. In all figures, an identical numeral is assigned to an element commonly appeared in the figures, and the detailed description thereof will not be repeated.

First Embodiment

FIG. 1A is a perspective view, illustrating an electronic device in first embodiment of the present invention, and FIG. 1B is a cross-sectional view, broken along line I-I' in FIG. 1A.

As shown in FIG. 1B, an electronic device **108** includes a light receiving element **101**, a frame member **102** composed of a first resin provided so as to surround a photo acceptor unit **101b** (functional unit) of the light receiving element **101**, and an encapsulating resin layer **106** composed of a second resin and filling a periphery of the frame member **102**. Though it is not shown in FIG. 1B, the electronic device **108** further

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includes a protective film that covers a plane formed by an upper surface of the frame member **102** and an upper surface of the encapsulating resin layer **106**. Further, a light receiving element **101** is electrically coupled to lead frames **104** through metal filaments **105**.

The upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** form a common plane. More specifically, since the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** are coplanar, an adhesion and a stripping of a protective film that covers the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** can be easily presented.

A photo acceptor unit **101b** serving as a functional unit is formed in the surface of the light receiving element **101**. More specifically, the photo acceptor unit **101b** is exposed in the surface of the light receiving element **101**.

The frame member **102** is formed on the light receiving element **101**, and is provided so as to surround the photo acceptor unit **101b**. The photo acceptor unit **101b** of the light receiving element **101** is exposed in a space surrounded by the frame member **102**.

A height of the frame member **102** is designed to be 0.08 mm. Preferable height of the frame member **102** may be equal to or larger than 0.05 mm, and more preferably equal to or larger than 0.1 mm. Such range of the height provides prevention from a contact of the metal filament **105** coupled between the lead frame **104** and the predetermined position of the light receiving element **101** with encapsulating metal molds **111a** and **111b** that are employed in the manufacturing process for the electronic device **108** (see FIG. 4A). Therefore, the encapsulating metal mold **111a** can be strongly adhered to the upper surface of the frame member **102**, preventing the encapsulating resin layer **106** from a permeation into the inside of the frame member **102**. Here, the height of the frame member **102** may be determined as a vertical length from the upper surface of the light receiving element **101** to the upper surface of the frame member **102**, and equivalent to a thickness of the resin film composed of the first resin.

Preferable elastic modulus of the frame member **102** may be within a range of from 1 GPa to 6 GPa at 20 degree C. and within a range of from 10 MPa to 3 GPa at 200 degree C. The range of from 1 GPa to 6 GPa at 20 degree C. provides a function of the frame member **102** as protecting the photo acceptor unit **101b** of the electronic device **108**. The range of from 10 MPa to 3 GPa at 200 degree C. provides a function of the frame member **102** as a cushioning material, as the frame member **102** is elastically slightly deformed when the frame member **102** is pressed to the encapsulating metal molds **111a** and **111b** in the process for manufacturing the electronic device **108**, so that the photo acceptor unit **101b** is protected from the external pressure. Here, the elastic modulus of the frame member **102** means an elastic modulus in the condition that the first resin is completely cured with a light and a heat.

The frame member **102** is formed of the first resin. The first resin is a cured product of a resin material that is curable by a light and a heat. The resin materials that are curable by a light and a heat include photo-reactive resins such as acrylic resins and heat-reactive resins such as epoxy resins.

The encapsulating resin layer **106** is formed of the second resin. The second resin is an encapsulating resin that is employed for encapsulating the electronic device **108**. The upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** totally form a flat surface.

A method for manufacturing the electronic device in first embodiment will be described in reference to FIG. 2A to FIG. 6B. FIG. 2A to FIG. 5C are cross-sectional views, illustrating

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a process for manufacturing the electronic device in first embodiment. FIG. 6A is a perspective view, illustrating the electronic device in first embodiment, and FIG. 6B is a cross-sectional view broken along line II-II' in FIG. 6A.

First of all, as shown in FIG. 2A, the wafer **101a** is prepared. Such wafer **101a** includes a plurality of light receiving elements **101** formed therein, and the photo acceptor units **101b** are exposed over the surface of the light receiving element **101**. Here, among the light receiving elements **101** arranged in the wafer **101a**, only two light receiving elements **101** are illustrated in FIG. 2A, and thus only two photo acceptor units **101b** are exposed.

Next, as shown in FIG. 2B, the resin film **102a** (first resin) is formed on the light receiving element **101** (wafer **101a**). Here, the resin film **102a** is a film having a uniform thickness distribution. The reason for employing such film-form resin film **102a** is to form a resin film having a uniform film thickness of 0.05 mm or thicker over the entire wafer **101a**. More specifically, a lower viscosity resin should be employed for obtaining uniform thickness of the film over the entire wafer **101a** in a case that a liquid resin is employed for the resin film **102a**, which leads to a difficulty in obtaining a sufficient film thickness of 0.05 mm due to its lower viscosity. On the contrary, a formation of a film having a thickness of 0.05 mm or larger over the entire wafer **101a** with a liquid resin requires a use of a higher viscosity resin, which leads to an increased viscous resistance during the process for coating thereof over the wafer **101a** due to its higher viscosity, causing an increased variation in the thickness of the coated film, such that it is difficult to obtain a uniform film thickness. Consequently, the use of the film-form resin film **102a** achieves forming the resin film **102a** with a uniform film thickness of 0.05 mm or thicker. In the present embodiment, the entire wafer **101a** is covered with the resin film **102a**. The thickness of the resin film **102a** is 0.08 mm. This configuration allows obtaining the frame member **102** having the height of 0.08 mm.

Subsequently, as shown in FIG. 2C, an alignment is performed so that the photo acceptor unit **101b** is disposed within an inner diameter of a cylindrical portion formed in the upper surface of the exposure mask **103**, and then an exposure is performed to pattern the resin film **102a** so as to form the frame member **102**.

Further, as shown in FIG. 2D, a developing process is performed to remove portions of the resin film **102a** except the frame members **102**, so that the frame members **102** is formed so as to surround the photo acceptor units **101b**. As described above, the frame members **102** can be formed by using a photolithographic process. Thus, a contact of the encapsulating resin layer **106** against the photo acceptor unit **101b** is completely eliminated, thereby preventing the encapsulating resin layer **106** from remaining in the inside of the frame member **102**. In addition to above, the resin composing the frame member **102** is not completely cured just after the developing process is completed, providing a weak adhesion between the frame member **102** and the wafer **101a** or in other words between the frame member **102** and the light receiving elements **101** with a weak adhesion force, and not providing a firm adhesion.

Subsequently, the frame member **102** having the wafer **101a** thereon is thermally processed to completely cure the frame member **102**, providing a firm adhesion the frame member **102** and the wafer **101a** or in other words between the frame member **102** and the light receiving elements **101**. Since no geometric change is caused in the frame member

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102 by such thermal processing, the geometry of the frame member 102 is similar to the geometry of the frame member 102 shown in FIG. 2D.

Subsequently, as shown in FIG. 3A, the individual light receiving elements 101 are diced out from the wafer 101a to obtain the light receiving elements 101 having the frame members 102.

As shown in FIG. 6A, the frame member 102 is formed to form a cylindrical shape having a hollow portion in the inside of the frame member. Here, the available geometry of the frame member 102 is not limited to a cylindrical geometry, and other column or prism such as an elliptical column or a square pole may alternatively be employed so as to form a frame around the photo acceptor unit 101b, depending on the geometry of the photo acceptor unit 101b. Further, since the upside of the photo acceptor unit 101b is provided with a hollow portion in the inside of the frame member 102 as shown in FIG. 6B, the photo acceptor unit 101b is exposed in the surface of the light receiving element 101. Here, an elastic modulus of the frame member 102 is controlled to be about 2.4 GPa at an ambient temperature, and about 15 MPa at a temperature of 200 degree C. The elastic modulus of the frame member 102 may be appropriately adjusted by suitably selecting a type of the resin material that is curable by a light and a heat or a content ratio of added agents such as a curing agent and the like, or a process conditions such as a curing light intensity or a curing temperature.

Subsequently, as shown in FIG. 3B, the light receiving element 101 is adhered in a predetermined position on the lead frame 104 by an adhesive agent. Subsequently, as shown in FIG. 3C, the light receiving elements 101 are electrically coupled to the associated lead frames 104 in respective predetermined positions by metal filaments 105.

Subsequently, as shown in FIG. 4A, encapsulating metal molds 111a and 111b having flat molding surfaces are prepared, and then the light receiving elements 101 on the lead frame 104 shown in FIG. 4B are fixed in predetermined positions of the encapsulating metal mold 111a and 111b. Subsequently, the molding surface of the encapsulating metal mold 111a compressively contacts with the upper surface of the frame member 102, and the molding surface of the encapsulating metal mold 111b compressively contacts with the lower surface of the lead frame 104. More specifically, a gap between the upper surface of the frame member 102 and the molding surface of the encapsulating metal mold 111a and a gap between the lower surface of the lead frame 104 and the molding surface of the encapsulating metal mold 111b are reduced to be minimum, providing close contacts therebetween.

Subsequently, as shown in FIG. 4A, staying at the condition of the compressive-contact, an encapsulating resin melted by a heat (second resin) is injected in spaces surrounded by the molding surfaces of the encapsulating metal molds 111a and 111b except the space surrounded by the frame member 102. This achieves forming the encapsulating resin layer 106 filling the periphery of the frame member 102. Here, an enclosed region surrounded by the frame member 102 and the encapsulating metal mold 111a is formed in the upside of the photo acceptor unit 101b. Further, the molding surface of the encapsulating metal mold 111a and the upper surfaces of the frame member 102 are closely contacted with an external force by a clamping pressure, and the light receiving element 101 and the frame member 102 are strongly adhered as described above. In such case, if the frame member 102 has an elastic modulus within a range of from 1 GPa to 6 GPa at 20 degree C. and within a range of from 10 MPa to 3 GPa at 200 degree C., the frame member 102 itself can be

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suitably elastically-deformed by a clamping pressure of the encapsulating metal mold to absorb the external force of such clamping pressure, thereby providing a protection for the light receiving element 101. Further, such elastic deformation may also create an opposing force for closely contacting the frame member 102 against the encapsulating metal mold 111a. Thus, an unwanted flow of the encapsulating resin into the interior of the frame member 102 or in other words into the enclosed region formed in the upside of the photo acceptor unit 101b can be prevented. In order to provide an increased adhesive force of the encapsulating metal mold 111a by the elastic deformation of the frame member 102 as described above, the design may be presented so that the height of the upper surface of the frame member 102 from the upper surface of the encapsulating resin layer 106 is within a range of from 0 mm to 0.05 mm. When the upper surface of the frame member 102 is designed to be higher than the upper surface of the encapsulating resin layer 106 by 0.05 mm or larger, the external force due to the clamping pressure of the encapsulating metal mold 111a is increased, a deformation of the frame member 102 may lead to a plastic deformation, causing a break of the frame member 102. On the contrary, if the upper surface of the frame member 102 is lower than the upper surface of the encapsulating resin layer 106, or in other words, if the height of the upper surface of the frame member 102 is lower than the height of the upper surface of the encapsulating resin layer 106 (lower than 0 mm level), causing an unwanted flow of the encapsulating resin has in the inside of the frame member 102.

Subsequently, the encapsulating metal molds 111a and 111b are removed to obtain the light receiving element 101, in which the level of the upper surface of the frame member 102 is the same as the level of the upper surface of the encapsulating resin 106, as shown in FIG. 4B. More specifically, a plurality of light receiving elements 101 on the lead frame 104 are totally encapsulated.

Subsequently, as shown in FIG. 5A, a protective tape 107 is formed to cover the upper surface of the frame member 102 and the upper surface of the encapsulating resin layer 106. The protective tape 107 serves as protecting the photo acceptor units 101b. Although the material for the protective tape 107 are not particularly limited to any specific material, a strippable resin having a heat resistance at a temperature of not lower than its reflow temperature may be typically employed.

Subsequently, as shown in FIG. 5B, a dicing into the respective light receiving elements 101 is performed to obtain the electronic device 108 having the desired geometry.

Then, the electronic device 108 is coupled to the base substrate 109 having the essential electric circuits formed therein by a solder 110 with a reflow process. The protective tape 107 is then removed to obtain the electronic device 108 having the installed devices FIG. 5C.

Here, the electronic device 108 is a device having a passive element and/or an active element formed on the surface of the semiconductor substrate or the glass substrate.

Advantageous effects obtainable by employing the configuration of the present embodiment will be described. The electronic device 108 is configured to have the upper surface of the frame member 102 and the upper surface of encapsulating resin layer 106, both of which form a common plane. According to electronic device 108 having such configuration, easy adhesion and removal of the protective tape 107 that covers the upper surface of the frame member 102 and the upper surface of the encapsulating resin layer 106 can be achieved. Therefore, a contamination in the photo acceptor unit 101b can be reduced. Since the protective tape 107 dis-

posed on the optical path of the exposed photo acceptor unit **101b** can be easily eliminated in the use of the electronic device **108**, an attenuation of the optical signal can be prevented. Thus, the electronic device **108** having an improved reliability can be achieved.

Further, the protective tape **107** is removed after the electronic device **108** is coupled to the base substrate **109** in the process for manufacturing the electronic device **108**. Therefore, a contamination in the photo acceptor unit **101b** by the contaminants entered in the inside of the frame member **102** can be inhibited during the installation of the electronic device **108** onto the base substrate **109**.

In the method for manufacturing of electronic device **108** includes the flat molding surfaces of the encapsulating metal mold **111a** and **111b** are pressed against the upper surface of the frame member **102** and the lower surface of the lead frame **104**, and the encapsulating resin is injected into the spaces surrounded by the molding surfaces of the encapsulating metal molds **111a** and **111b** except the space surrounded by the frame member **102** to form the encapsulating resin layer **106** that fills the periphery of the frame member **102**. Therefore, the structure, in which the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** form a common plane, can be obtained by a simple process. Thus, an improved productivity of the electronic devices **108** can be achieved.

Further, the use of the resin film **102a** having uniform thickness distribution can provide the frame member **102** having the uniform height distribution over the entire surface of the wafer **101a**. This allows reducing the variation in the height of the frame member **102** on the light receiving element **101**, and providing the encapsulating in one process. Thus, an improved productivity of the electronic devices **108** can be achieved.

Further, the frame member **102** provides a protection for the photo acceptor units **101b** in the process for manufacturing the electronic device **108**, and the removal of the frame member **102** after the production of the electronic device **108** is not required. Therefore, an additional operation for removing the frame member **102** can be omitted, so that the electronic device **108** exhibiting an improved reliability can be obtained without a need for conducting additional manufacturing processes.

While the exemplary implementation of the resin film **102a** having the thickness of 0.08 mm is shown in the present embodiment, the thickness of the resin film **102a** may be suitably selected, and the height of the frame member **102** may be selected to be equal to or larger than 0.08 mm, and more preferably thicker resin film **102a** of 0.1 mm or thicker may be employed. In addition, while the exemplary implementation employing a single layer of the resin film **102a** is illustrated in the present embodiment, the resin film **102a** may include any number of layers.

Second Embodiment

FIGS. 7A to 7C are cross-sectional views, illustrating a manufacturing process for an electronic device in second embodiment. While first embodiment is configured to adopt the protective tape **107**, the present embodiment is configured to adopt a protective glass **207**. Other configurations of the present embodiment are similar to that employed in first embodiment.

The protective glass **207** is formed on a plane commonly formed by the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106**. An optically transparent glass may be employed for the protective glass **207**.

In the process for manufacturing the electronic device **208** having such configuration, the similar manufacturing process operations shown in FIG. 2A to FIG. 4B for manufacturing the electronic device **108** in the previous embodiment may also be employed. Here, manufacturing process operations after the operations shown in FIG. 2B will be described.

First of all, as shown in FIG. 7A, the protective glass **207** is adhered to cover the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106**. Here, the adhesion of the protective glass **207** is achieved with an adhesive agent having a heat resistance at a temperature of not lower than its reflow temperature. Next, as shown in FIG. 7B, each of a plurality of electronic devices **208** formed on the lead frame **104** is diced out to obtain the electronic devices **208** having desired geometry. Next, as shown in FIG. 7C, the electronic device **208** is coupled to the base substrate **109** having the essential electric circuits formed therein by a solder **110** with a reflow process, and then is installed.

Since the optically transparent glass is employed for the protective glass **207** for the electronic device **208** in second embodiment, an advantageous effect of eliminating unwanted operation for stripping the protective glass **207** after the end of the reflow operation can be provided.

The present embodiment is also configured that the upper surface of the frame member **102** and the upper surface of the encapsulating resin layer **106** form a common plane, so that the electronic device **208** that is easily provided with the protective glass **207** adhered thereon, and the process for manufacturing thereof, can be achieved. Other advantageous effects of the present embodiment are similar to that obtained in the above-described embodiment.

Third Embodiment

FIGS. 8A to 8D are cross-sectional views, illustrating a process for manufacturing an electronic device in third embodiment. The configuration of the electronic device in third embodiment is similar to that of the electronic device **108** in first embodiment.

The frame member **302** of the electronic device in third embodiment is formed by the manufacturing process as shown in FIGS. 8A to 8D. Other manufacturing process operations in this embodiment are similar to the operations in first embodiment. FIG. 8A to FIG. 8D correspond to FIG. 2A to FIG. 2D, respectively. Other manufacturing process operations are similar to the operations in first embodiment, and thus the detailed description thereof is not repeated.

First of all, as shown in FIG. 8A, a wafer **101a** having a plurality of light receiving elements **101** formed therein is prepared. The photo acceptor units **101b** are exposed in the surfaces of respective light receiving elements **101** arranged in the wafer **101a**. Here, among a plurality of light receiving elements **101** arranged in the wafer **101a**, only two light receiving elements **101** are illustrated in FIG. 8A. In addition, a resin film **302a** formed to have a film-form and composed of a resin material that is curable by a light and a heat is prepared. Openings corresponding to the hollow sections of the frame member **302** are previously bored in the resin film **302a**. Next, as shown in FIG. 8B, an alignment for the photo acceptor units **101b** is performed to be suitably positioned in the inside of the opening provided in the resin film **302a**, and then the entire light receiving element **101** (wafer **101a**) is covered with the resin film **302a**.

Then, as shown in FIG. 8C, an exposure process is performed by employing an exposure mask **103** to pattern the resin film **302a** so as to form the frame member **302**.

Further, as shown in FIG. 8D, a developing process is performed to remove the resin film **302a** except the frame members **302**, so that the frame members **302** provided to

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surround the respective photo acceptor units **101b** are formed. As described above, the frame member **302** can be formed by employing a photolithographic process. In addition to above, the resin composing the frame member **302** is not completely cured just after the developing process is completed, providing a weak adhesion between the frame member **302** and the light receiving elements **301** with a weak adhesion force, and not providing a firm adhesion.

So that an inner hollow portion of frame member **302** is previously formed, a residue of the resin film **302a** inside of the frame member **302**, which is otherwise difficult to be completely eliminated by only the developing process, can be prevented. Therefore, a contamination in the photo acceptor unit **101b** can be further inhibited, and thus the electronic device **108** exhibiting a further improved reliability and the method for manufacturing thereof can be achieved. While the manufacturing process, in which the inner wall and the external wall of the frame member **102** are simultaneously formed, is difficult to form the inner wall of the frame member **102** as being perpendicular to the surface of the light receiving element **101** as described in first embodiment, the use of the frame member **302** as described in third embodiment can provide a formation of the inner wall of the frame member **302** as being perpendicular to the surface of the light receiving element **101**, by previously forming the openings in the resin film **302a**. Thus, the distance between the photo acceptor unit **101b** and the frame member **302** can be reduced, thereby further reducing a contamination in the photo acceptor unit **101b**. In addition, further advantageous effect of allowing a reduction in the size of the electronic device is also achieved.

In the present embodiment, the configuration of the electronic device is also similar to that of first embodiment. Other advantageous effects of the present embodiment are similar to that obtained by the above-described embodiment.

Fourth Embodiment

FIGS. **9A** and **9B** are cross-sectional views, illustrating a process for manufacturing an electronic device in fourth embodiment. Configuration of the electronic device in fourth embodiment is similar to that for the electronic device **108** in first embodiment. The electronic device in fourth embodiment is formed by the manufacturing process that is illustrated in FIGS. **9A** and **9B**. Other manufacturing process operations in this embodiment are similar to the operations in first embodiment. FIGS. **9A** and **9B** correspond to FIGS. **4A** and **4B**, respectively. Other manufacturing process operations are similar to the operations in first embodiment, and thus the detailed description thereof is not repeated.

First of all, as shown in FIG. **9A**, encapsulating metal molds **111a** and **111b** having flat molding surfaces are prepared, and then a resin film **412** is put on the molding surface of the encapsulating metal mold **111a** by a vacuum chucking. Successively, the light receiving elements **101** on the lead frame **104** are fixed in predetermined positions of the encapsulating metal mold **111a** and **111b**. Next, the molding surface of the encapsulating metal mold **111a** compressively contacts with the upper surface of the frame member **402**, and the molding surface of the encapsulating metal mold **111b** compressively contacts with the lower surface of the lead frame **104**. More specifically, the resin film **412** is disposed and pressed between the upper surface of the frame member **402** and the molding surface of the encapsulating metal mold **111a**.

This allows reducing a gap between the upper surface of the frame member **402** and the molding surface of the encapsulating metal mold **111a** and a gap between the lower surface of the lead frame **104** and the molding surface of the encap-

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sulating metal mold **111b** to be minimum by interposing the resin film **412**, providing close contacts therebetween.

Subsequently, as shown in FIG. **9B**, staying at the condition of the compressive-contact, an encapsulating resin melted by a heat is injected in spaces surrounded by the molding surfaces of the encapsulating metal molds **111a** and **111b** except the space surrounded by the frame member **102** to form an encapsulating resin layer **106** that fills the periphery of the frame member **402**. Here, an enclosed region surrounded by the frame member **402** and the encapsulating metal mold **111a** is formed in the upside of the photo acceptor unit **101b**. Further, the molding surface of the encapsulating metal mold **111a** and the upper surfaces of the frame member **402** are closely contacted with an external force by a clamping pressure, and the light receiving element **101** and the frame member **402** are strongly adhered as described above. Thus, an unwanted flow of the encapsulating resin into the interior of the frame member **402** or in other words into the enclosed region formed in the upside of the photo acceptor unit **101b** can be prevented.

Subsequently, the encapsulating metal molds **111a** and **111b** are removed to obtain the light receiving element **101** as shown in FIG. **9B**. More specifically, a plurality of light receiving elements **101** on the lead frame **104** are totally encapsulated. Since the resin film **412** is chucked to the encapsulating metal mold **111a** in such occasion, the film is not remained on the upper surface of the frame member **402** or on the upper surface of the encapsulating resin layer **106**.

In the present embodiment, an elastic modulus of the frame member **402** is 9 GPa. Therefore, an improved stiffness of the frame member **402** is achieved to provide a further strengthened protection for a permeation of the encapsulating resin into the hollow portion in the frame member **402**, providing a further improved protection for the photo acceptor unit **101b**.

When the elastic modulus of the frame member **402** of equal to or higher than 6 GPa is employed without employing the configuration of the present embodiment, a sufficient elastic deformation of the frame member **402** cannot possibly be presented against a direct clamp-pressurizing for the upper surface of the frame member **402** with the encapsulating metal mold **111a** as described above, so that it is possible to exert an external force generated by the clamping pressure over the light receiving element **101**. This may cause a breakdown of the light receiving element **101**, impairing the function of the photo acceptor unit **101b**, and further possibly causing deterioration in environmental tests. On the contrary, since the resin film **412** is interleaved between the upper surface of the frame member **402** and the molding surface of the encapsulating metal mold **111a** in the present embodiment, the resin film **412** functions as a cushioning material, so that defective situations typically as a breakdown of the light receiving element **101** or a disturbance of the function of the photo acceptor unit **101b** can be avoided.

Since the available range of the elastic modulus of the frame member **402** is equal to or higher than 6 GPa, a degree of flexibility in selecting a resin for the first resin as a material of the frame member **402** can be increased. Further advantage is that an increased stiffness of the frame member **402** can be presented since the frame member **402** is composed of the material of the resin having the elastic modulus of the completely cured resin of 9 GPa, so that a further strengthened protection for a permeation of the encapsulating resin into the photo acceptor unit **101b** can be achieved during the encapsulating process.

Here, the elastic modulus of frame member **402** means an elastic modulus of the product in the status of completely cured by a light and a heat. The frame member **402** is com-

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posed of the first resin. The first resin is a cured product of a resin material that is curable by a light and a heat cure. The resin materials that are curable by a light and a heat include photo-reactive resins such as acrylic resins and heat-reactive resins such as epoxy resins.

The elastic modulus of the resin film **412** is 3 GPa. Therefore, the resin film **412** is elastically deformed to function as a cushioning material when the upper surface of the frame member **402** is pressed to the encapsulating metal mold **111a**, so that the photo acceptor units **101** are protected. Light receiving element **101** can be protected.

While the exemplary implementation having the resin film **412** disposed between the upper surface of the frame member **402** and the molding surface of the encapsulating metal mold **111a** is illustrated in the present embodiment, a similar resin film may alternatively be disposed between the lower surface of the lead frame **104** and the molding surface of the encapsulating metal mold **111b** and may be pressed against thereof. Such alternative configuration prevents the melted encapsulating resin from entering into a gap between the lower surface of the lead frame **104** and the molding surface of the encapsulating metal mold **111b**.

Fifth Embodiment

FIG. **10A** is a perspective view, illustrating an electronic device in fifth embodiment, and FIG. **10B** is a cross-sectional view along line in FIG. **10A**. While the first embodiment is configured that the upper surface of the frame member and the upper surface of the encapsulating resin layer form a common plane, the present embodiment is configured that the upper surface of the frame member is higher than the upper surface of the encapsulating resin layer and protrudes toward the upper side. A process for manufacturing the electronic device in fifth embodiment is similar to the process for manufacturing the electronic device in first embodiment as shown in FIG. **2A** to FIG. **5C**.

A variation of a height of a frame member **502** in the process for manufacturing an electronic device in experimental manufactures was about 10 micrometer by standard deviation. Here, the variation of the height of the frame member **502** is a difference in the height of the frame member **502**, which is possibly caused due to changes in light intensity in an exposure process or changes in type of developing solution or in processing time in an developing process during the operation of forming the frame member **502** in the process for forming the film composed of the first resin and having a uniform thickness by a photolithographic process. Taking such variation of height in the manufacturing process into account, if the minimum height of the frame member **502** is designed to be not higher than the encapsulating resin layer **106**, the second resin (encapsulating resin) may possibly be entered in the interior of the frame member **502**, destroying the hollow portion.

On the contrary, in the electronic device of the present embodiment, the upper surface of the frame member **502** is higher than the upper surface of the encapsulating resin layer **106** by 10 micrometers to 60 micrometers, as shown in FIG. **10A**. The height of the frame member **502** that satisfies the above-described criterion may be obtained by designing the frame member **502** to be higher than the upper surface of the encapsulating resin layer **106** by about 30 micrometers, which is threefold of the standard deviation of the variation in the height of the frame member **502**. Such design of the height of the frame member **502** may also be suitably achieved by suitably adjusting a pressure for pressing against the frame member **502** in the encapsulating operation or the like.

Advantageous effects obtained in the electronic device of fifth embodiment are similar to that obtained in first embodi-

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ment. In addition, even if the upper surface of frame member **502** is higher than the upper surface of the encapsulating resin layer **106** by threefold of the standard deviation of the variation in the height of the frame member **502**, unwanted permeation of the encapsulating resin into the hollow portion of the frame member **502** can be inhibited, and therefore the configuration of the present embodiment can provide the electronic device that exhibits an improved reliability. Consequently, even if a variation in the height of the frame member **502** of about 10 micrometers by standard deviation is caused in the process for manufacturing the electronic device, an unwanted permeation of the encapsulating resin in the interior of the frame member **502**, which leads to a breakdown of the hollow portion and a contamination of the photo acceptor unit **101b**, can be inhibited.

Further, as shown in FIG. **10B**, the configuration of the upper surface of the frame member **502**, which is higher than the upper surface of the encapsulating resin layer **106** can provide a larger pressure applied to the frame member **502** when the frame member is pressed against the molding surfaces of the encapsulating metal molds **111a** and **111b** (see FIG. **4A**). Therefore, a further strengthened protection for a permeation of the encapsulating resin into the hollow portion in the frame member **502** can be achieved, providing a further improved protection for the photo acceptor unit **101b**.

Sixth Embodiment

FIGS. **11A** to **11G** are cross-sectional views, illustrating a manufacturing process of an electronic device in sixth embodiment.

While the frame member in first embodiment is formed of a single layer of the first resin, an electronic device in sixth embodiment is configured that a frame member is formed of laminated two plies of films composed of first resin and thus is configured of double layers having larger height. Other configurations of the present embodiment are similar to first embodiment. A frame member **602** of the electronic device in sixth embodiment is formed by the manufacturing process that is illustrated in FIGS. **11A** to **11G**. Other manufacturing process operations are similar to the operations in first embodiment, and thus the detailed description thereof is not repeated.

First of all, as shown in FIG. **11A**, a wafer **101a** is prepared.

The wafer **101a** is provided with a plurality of light receiving elements **101** formed therein, and photo acceptor units **101b** are exposed in the surfaces of respective light receiving elements **101**. Here, among a plurality of light receiving elements **101** arranged in the wafer **101a**, only two light receiving elements **101** are illustrated in FIG. **11A**, and two photo acceptor units **101b** are exposed.

Next, as shown in FIG. **11B**, resin films **602a** and **602b** formed to have a film-form having a thickness of 0.06 mm and composed of a resin material that is curable by a light and a heat are prepared. The resin film **602a** and the resin film **602b** are passed through a roll **603a** and a roll **603b** of a roller while a pressure is exerted thereon by a roll laminator process to obtain a laminated member so that a resin film **602c** having substantially no "distortion" or "wrinkle" is obtained. Since a film having uniform thickness is employed for each of the resin films **602a** and **602b**, the resin film **602c** composed of the laminated member of the resin film **602a** and the resin film **602b** is also a film having a uniform thickness (FIG. **11C**).

Next, as shown in FIG. **11D**, the resin film **602c** is installed on the light receiving element **101** (wafer **101a**) by a vacuum laminator process so that substantially no bubble or the like is generated in the contact surface between the resin film **602c**

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and the wafer **101a**, thereby covering the entire wafer **101a** with the resin film **602c**. The thickness of the resin film **602c** is 0.12 mm.

Then, as shown in FIG. 11E, an exposure process is performed by employing an exposure mask **103** to pattern the resin film **602c**, thereby forming the frame member **602**.

Further, as shown in FIG. 11F, a developing process is performed to partially remove the resin film **602c** except the corresponding portions of the frame members **602**, so that the frame members **602** provided to surround the associated photo acceptor units **101b** are formed. An experimental manufacture shows that the frame member **602** of the resin film **602c**, which is composed a laminated member of the resin film **602a** and the resin film **602b**, can be formed by employing a photolithographic process.

Advantageous effects obtained in the electronic device of sixth embodiment are similar to that obtained in first embodiment. In the present embodiment, the resin film **603c** is composed of dual-layered film-form resins of the first resin. This allows ensuring the sufficient thickness of resin film **603c** to be equal to or larger than 0.08 mm. Solvent employed in handling the first resin is necessary to be removed for providing a form of a film. In consideration of the removal of the solvent, a use of a thicker resin film **603c** having a thickness of larger than 0.08 mm causes a difficulty in removing the solvent therefrom. More specifically, it is difficult to eliminate a solvent from a product such as a film. Consequently, the use of the laminated member of the two films having a thickness of equal to or less than 0.08 mm, which allows easier removal of the solvent and easier processing, or in other words, the use of the laminated member of the film-formed first resins, provides an increased film thickness of the resin film **603c**.

In addition, the lamination process of the resin films **602a** and **602b** is completed in advance before forming the laminated resin film **602c** on the wafer **101a**, so that a creation of a "distortion" or a "wrinkle" in the resin films **602a** and **602b** (resin film **602c**) due to an adhesiveness or a stickiness between the resin films **602a** and **602b** can be reduced. More specifically, in the case of forming the resin films **602a** and **602b** in sequence on the wafer **101a**, when the first ply of resin film, namely the resin film **602a** for example, is formed and then the second ply of resin film, namely the resin film **602b** for example, is formed, a creation of a "distortion" or a "wrinkle" in the resin films **602a** and **602b** (resin film **602c**) due to the stickiness of the resin films **602a** and **602b** can be reduced.

In addition, the above-mentioned roll laminator process may be employed for forming the laminated member of the resin films **602a** and **602b**. The roll laminator process provides limited locations of the pressed sites in the resin films **602a** and **602b**, and thus, even if the stickiness of the resin films causes a "distortion" or a "wrinkle", such smaller "distortion" or "wrinkle" may be compensated to larger non-pressed sites in the resin films **602a** and **602b**, resulting in forming the laminated member of the resin films with substantially no "distortion" or "wrinkle".

Alternatively, a vacuum laminator process may also be employed in the process for forming the laminated member of the resin film **602c** on the wafer **101a**. More specifically, a use of the vacuum laminator process allows an easier defoaming from the interface between the wafer **101a** and the resin film **602c**, and also allows uniformly pressurizing over the entire wafer **101** even if a thinner wafer **101a** is employed, thereby avoiding a crack created in the wafer **101a**.

The use of the laminated member of the resin films for forming the frame member **602** allows providing an increased

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height of the frame member **602**, which leads to an increased distance between an apex of the metal filament **105** and the encapsulating metal molds **111a** and **111b**, so that an unwanted contact with the metal filament **105** can be prevented with an increased distance (see FIG. 11G). Further, an increased height of the frame member **602** allows providing an increased flexibility in the design for the heights of the encapsulating resin layer **106** and the frame member **602**. As described in first embodiment, the permitted difference between the vertical dimension (height) of the frame member **602** and the vertical dimension (thickness) of the encapsulating resin layer **106** is equal to or smaller than 0.05 mm. While maintaining such range of the permitted difference in the vertical dimension, the vertical dimension or the height of the frame member **602** itself may be further increased by increasing the vertical dimension or the thickness of the encapsulating resin layer **106**. Such increased height of the frame member **602** provides larger elastic deformation of the frame member **602**, leading to a creation of larger reactive force, which, in turn, creates a stronger contact between the frame member **602** and the encapsulating metal mold **111a**, thereby preventing the encapsulating resin layer **106** from entering in the interior of the frame member **602**. Conversely, such increase in the height of the frame member **602** ensures sufficient thickness of the encapsulating resin layer **106**, leading to providing sufficient protection with the encapsulating resin without exposing the light receiving element **101** and the metal filament **105**, while ensuring the height of the frame member **602** from the encapsulating resin layer **106** to be up to 0.05 mm.

The electronic device and the process for manufacturing thereof according to the present invention are not limited to the above-described embodiments, and various modifications may be available.

While the exemplary implementations for employing the light receiving elements **101**, which are the elements available in digital video disc (DVD) systems, are, for example, illustrated in the above-described embodiments, imaging devices employed for digital video cameras or digital still cameras, various types of micro-electro-mechanical systems (MEMS) and electro-acoustic filters utilizing an electric oscillation may also be employed. Further, the configurations of the present invention may also be employed for semiconductor devices that requires an air space around the elements, which is requires due to a requirement for a lower dielectric constant. In addition, while the base member is described by illustrating a lead frame, the base member is not limited to lead frames, and a resin substrate or a film-form substrate, for example, may alternatively be adopted.

It is apparent that the present invention is not limited to the above embodiment, and may be modified and changed without departing from the scope and spirit of the invention.

What is claimed is:

1. A method for manufacturing an electronic device, said method comprising:

forming a resin film over a wafer, the wafer comprising a plurality of elements formed therein, and each of the elements comprising a functional unit;

patterning the resin film to form a plurality of frame members, each of the frame members being provided on said each of the elements to surround each functional unit;

providing an encapsulation by:

installing at least one of the elements over a base member;

pressing a molding surface of a first encapsulating metal mold and a molding surface of a second encapsulating metal mold against an upper surface of at least one of

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said frame members and against a lower surface of the base member, respectively;
 injecting an encapsulating resin into a space between the molding surfaces of the first and second encapsulating metal molds but other than into a space surrounded by each frame member, thereby forming an encapsulating resin layer in a periphery of each frame member; and
 removing the first and second encapsulating metal molds after said injecting;
 after said removing the first and second encapsulating metal molds, forming a protective film over the upper surface of the frame member and over an upper surface of the encapsulating resin layer so that each functional unit is exposed to the protective film;
 dividing the wafer including the protective film into divided wafer portions each comprising one of said elements; and
 removing the protective film from said each of the wafer portions divided as a result of said dividing of the wafer, wherein the upper surface of the frame member is located higher than the upper surface of the encapsulating resin layer after said removing the first and second encapsulating metal molds.

2. The method as set forth in claim 1, wherein said forming of the resin film comprises:
 laminating a plurality of film-form resins; and
 disposing the lamination over the wafer.

3. The method as set forth in claim 2, wherein said laminating is performed by a roll laminator process, and wherein said disposing of the resin film is performed by a vacuum laminator process.

4. The method as set forth in claim 1, wherein the protective film covers the functional unit.

5. The method as set forth in claim 1, wherein the resin film comprises a plurality of previously formed openings each corresponding to a position of the functional unit located on the wafer.

6. The method as set forth in claim 1, wherein a film is disposed and pressed between the upper surface of the frame member and the molding surface of the first encapsulating metal mold during said providing of the encapsulation.

7. The method as set forth in claim 1, wherein a film is disposed and pressed between the lower surface of the base member and the molding surface of the second encapsulating metal mold during said providing of the encapsulation.

8. The method as set forth in claim 1, wherein the base member and the encapsulating resin layer are divided into individual packages as a result of said dividing of the wafer.

9. The method as set forth in claim 1, wherein the upper surface of the frame member is located higher than the upper surface of the encapsulating resin layer by 10 micrometers to 60 micrometers.

10. The method as set forth in claim 1, wherein the protective film comprises a strippable resin having a heat resistance at a temperature of not lower than a reflow temperature of the strippable resin.

11. The method as set forth in claim 1, wherein said dividing of the wafer comprises dicing the wafer into diced wafer portions each comprising one of said elements, and each diced wafer portions forming a light receiving element.

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12. The method as set forth in claim 1, further comprising: after said dividing of the wafer, coupling said each of the wafer portions to a substrate by a solder.

13. The method as set forth in claim 12, wherein said coupling said each of the wafer portions is performed before said removing of the protective film.

14. A method for manufacturing an electronic device, said method comprising:
 forming a resin film over a wafer, the wafer comprising a plurality of elements formed therein, and each of the elements comprising a functional unit;
 patterning the resin film to form a plurality of frame members, each of the frame members being provided on said each of the elements to surround each functional unit;
 installing at least one of the elements over a base member;
 pressing a molding surface of a first encapsulating metal mold and a molding surface of a second encapsulating metal mold against an upper surface of at least one of said frame members and against a lower surface of the base member, respectively;
 injecting an encapsulating resin into a space between the molding surfaces of the first and second encapsulating metal molds but outside of a space surrounded by each frame member, thereby forming an encapsulating resin layer in a periphery of each frame member;
 removing the first and second encapsulating metal molds after said injecting;
 after said removing the first and second encapsulating metal molds, forming a protective film over the upper surface of the frame member and over an upper surface of the encapsulating resin layer so that each functional unit is exposed to the protective film;
 dividing the wafer including the protective film into divided wafer portions each comprising one of said elements; and
 removing the protective film from each of the wafer portions divided as a result of said dividing of the wafer.

15. The method as set forth in claim 14, wherein, after said removing the first and second encapsulating metal molds, with respect to an upper surface of the base member, the upper surface of the frame member is located at least at a same height as the upper surface of the encapsulating resin layer.

16. The method as set forth in claim 14, wherein, after said removing the first and second encapsulating metal molds, with respect to an upper surface of the base member, the upper surface of the frame member is located higher than the upper surface of the encapsulating resin layer.

17. The method as set forth in claim 14, wherein the upper surface of the frame member is located higher than the upper surface of the encapsulating resin layer in a range from 0 mm to 0.05 mm.

18. The method as set forth in claim 14, wherein the protective film comprises a strippable resin having a heat resistance at a temperature of not lower than a reflow temperature of the strippable resin.

19. The method as set forth in claim 14, wherein said dividing the wafer comprises dicing the wafer into diced wafer portions each comprising one of said elements, and each diced wafer portion forming a light receiving element.

20. The method as set forth in claim 14, further comprising: after said dividing of the wafer, coupling said each of the wafer portions to a substrate by a solder, wherein said coupling said each of the wafer portions is performed before said removing of the protective film.

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